

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant	:	Chou San Nelson Loke, et al.
Appl. No.	:	10/781,247
Filed	:	February 18, 2004
For	:	SYSTEM AND METHOD OF CVD CHAMBER CLEANING
Examiner	:	Keath Chen
Group Art Unit	:	1709

AMENDMENT AND RESPONSE TO FINAL OFFICE ACTION**Mail Stop: AF**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Final Office Action electronically sent on December 26, 2008, please reconsider the present application in light of the following amendments and comments.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 4 of this paper.